

Fig. 1

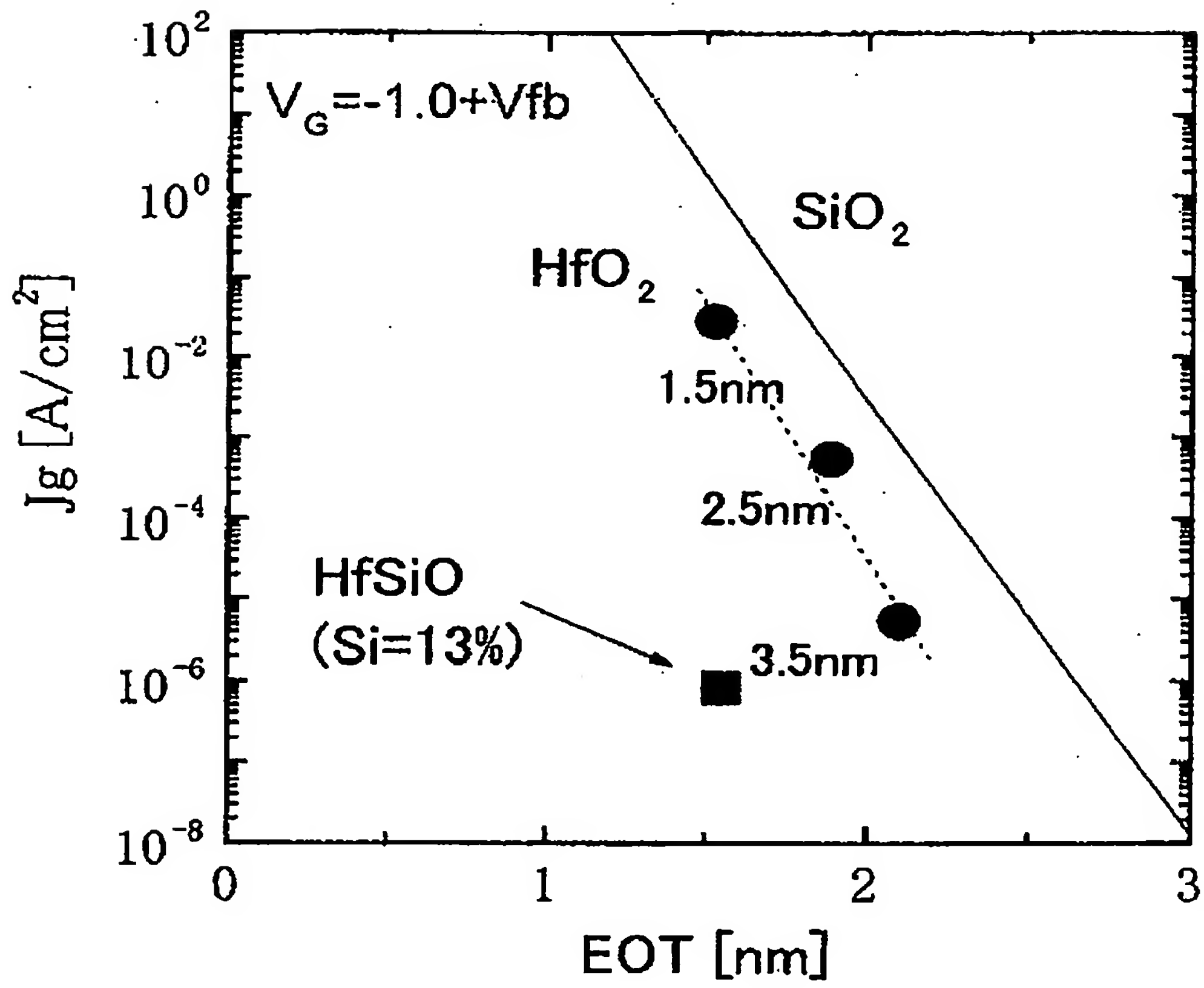


Fig. 2

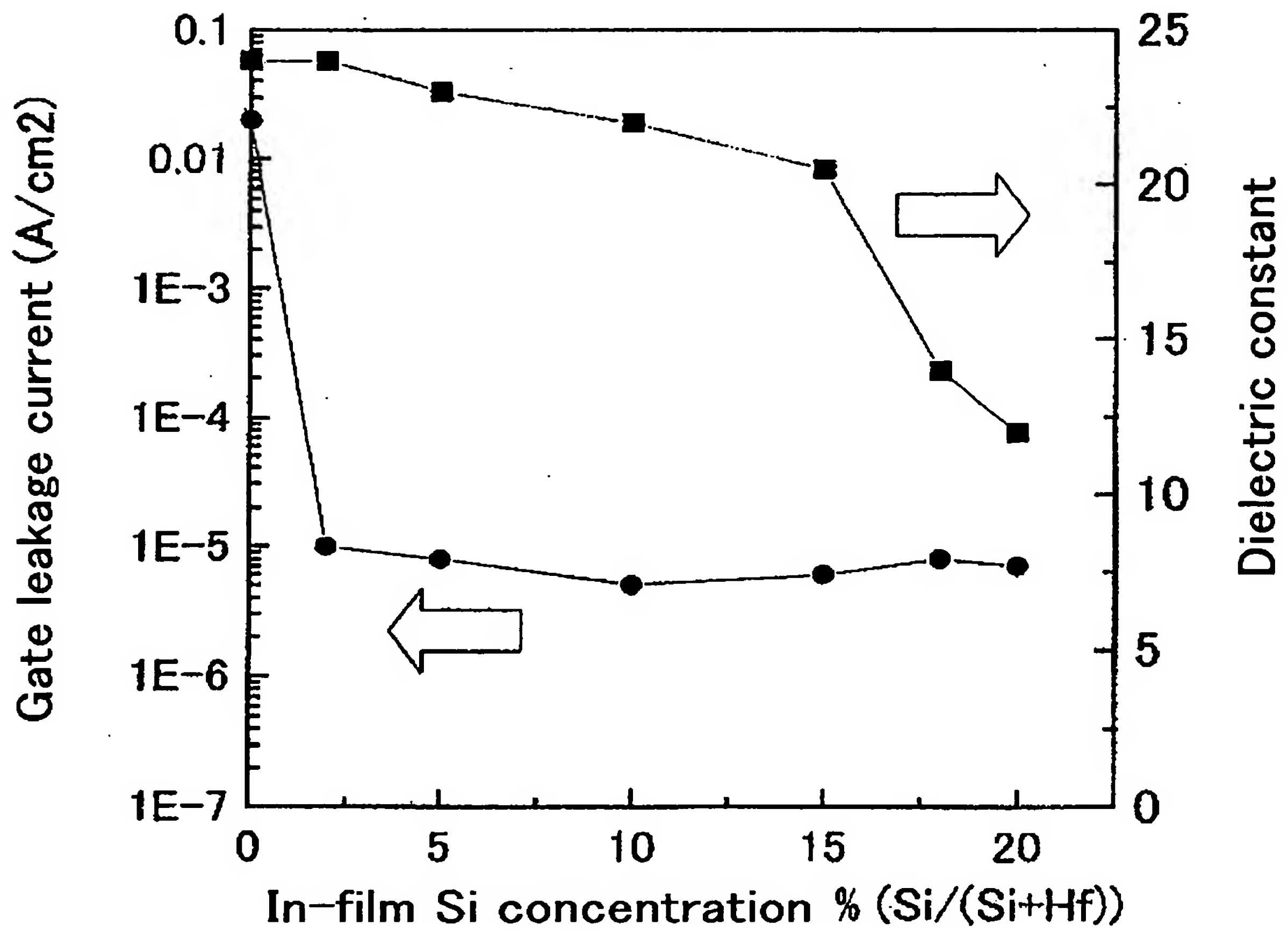


Fig. 3

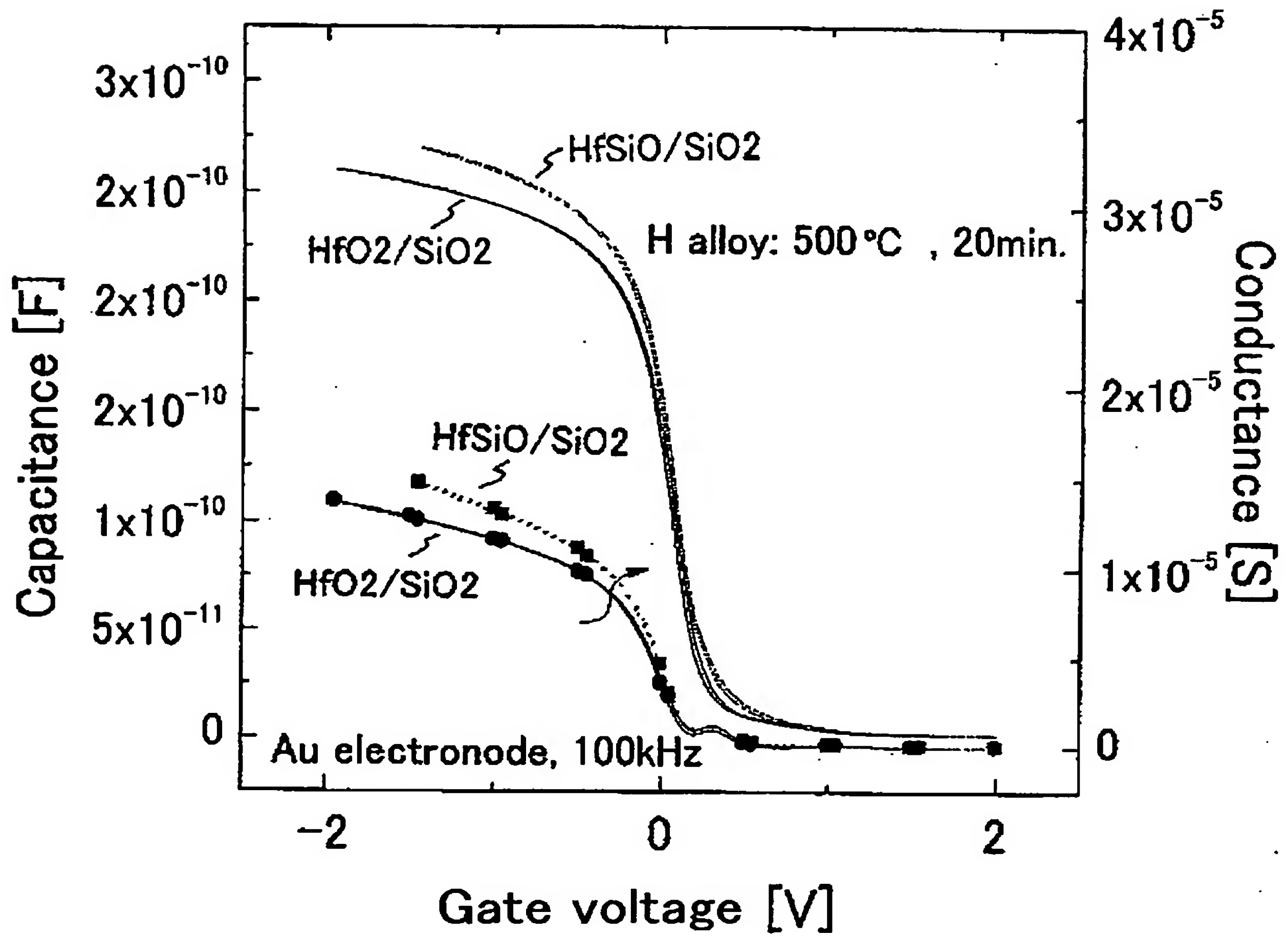


Fig. 4

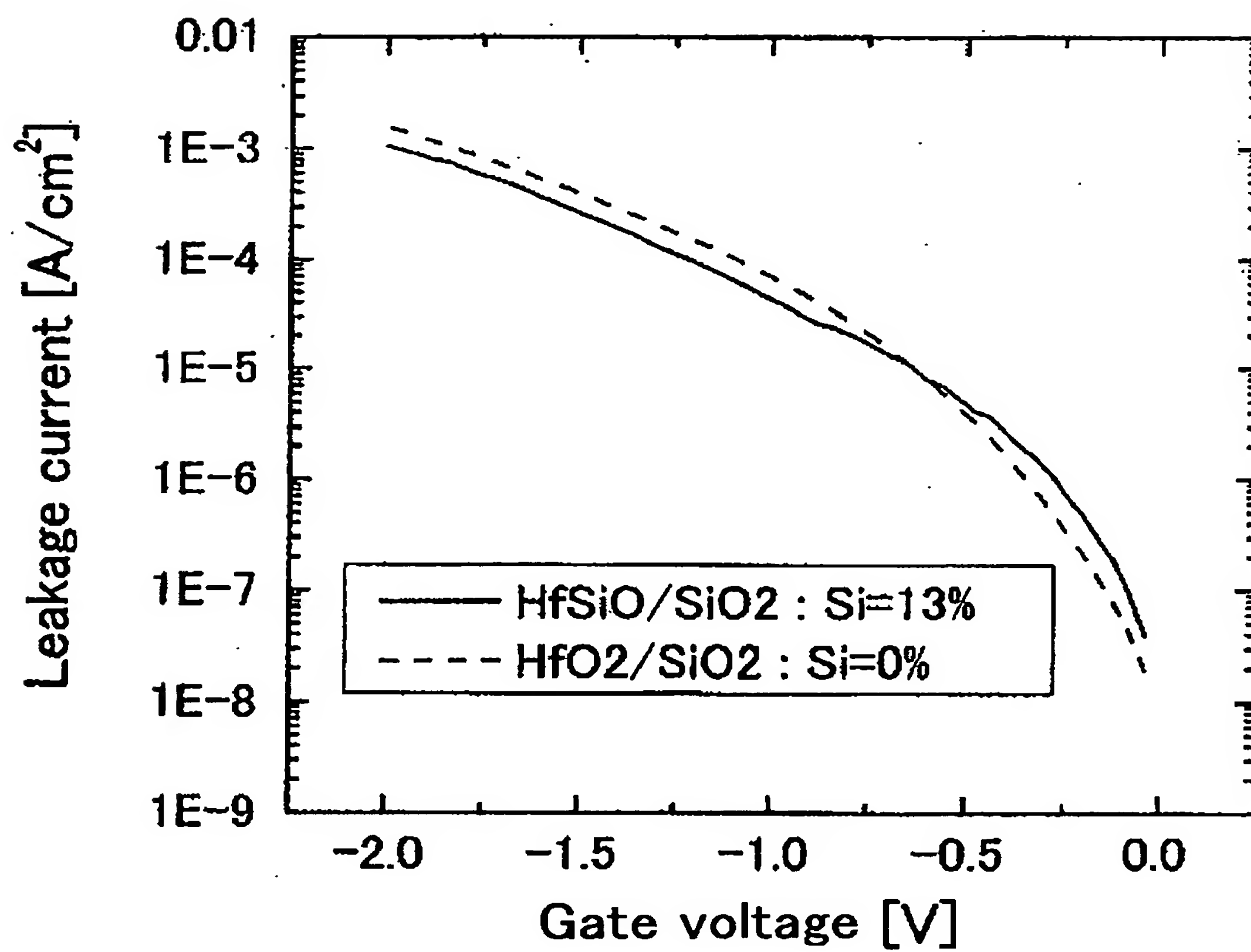


Fig. 5

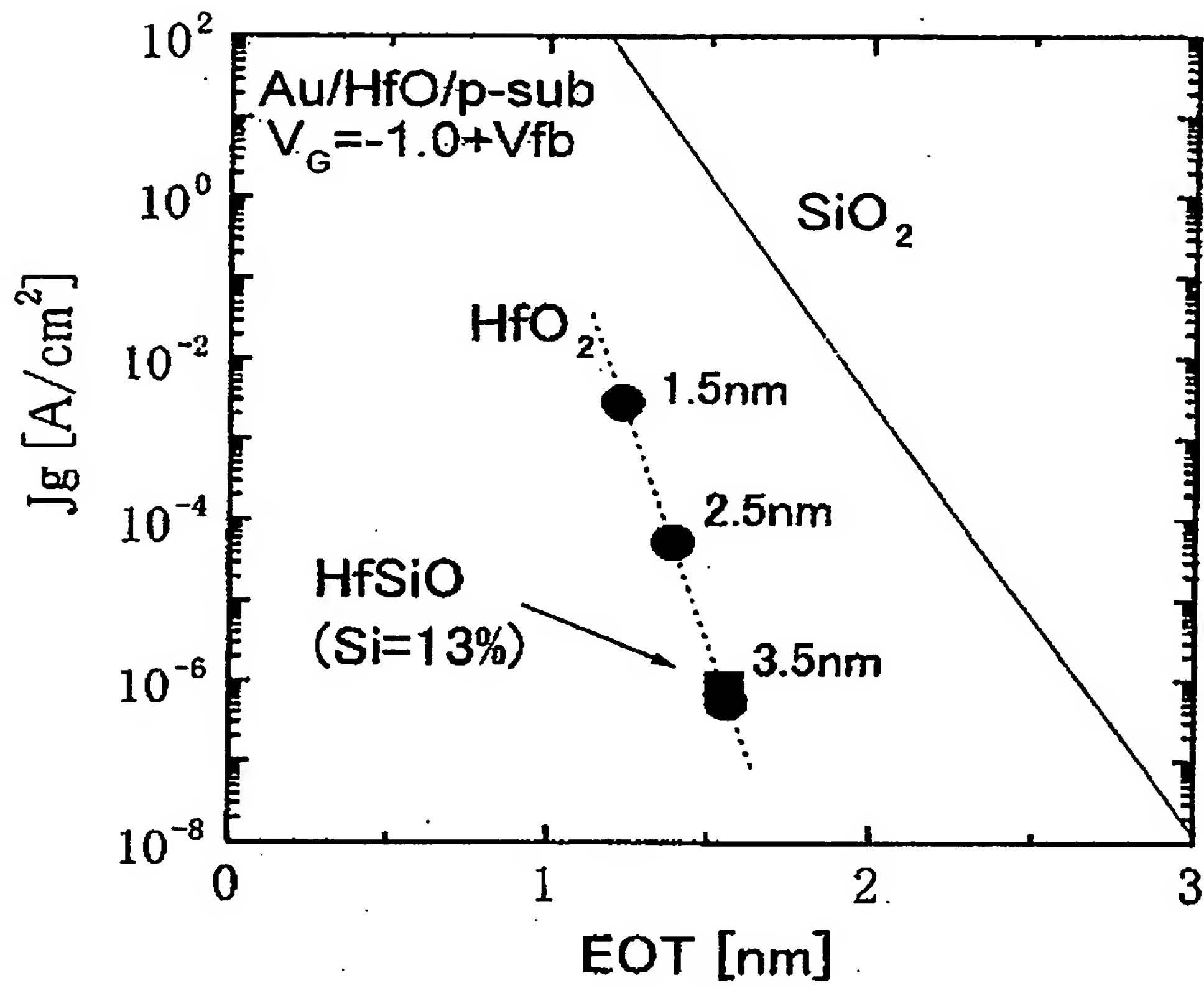
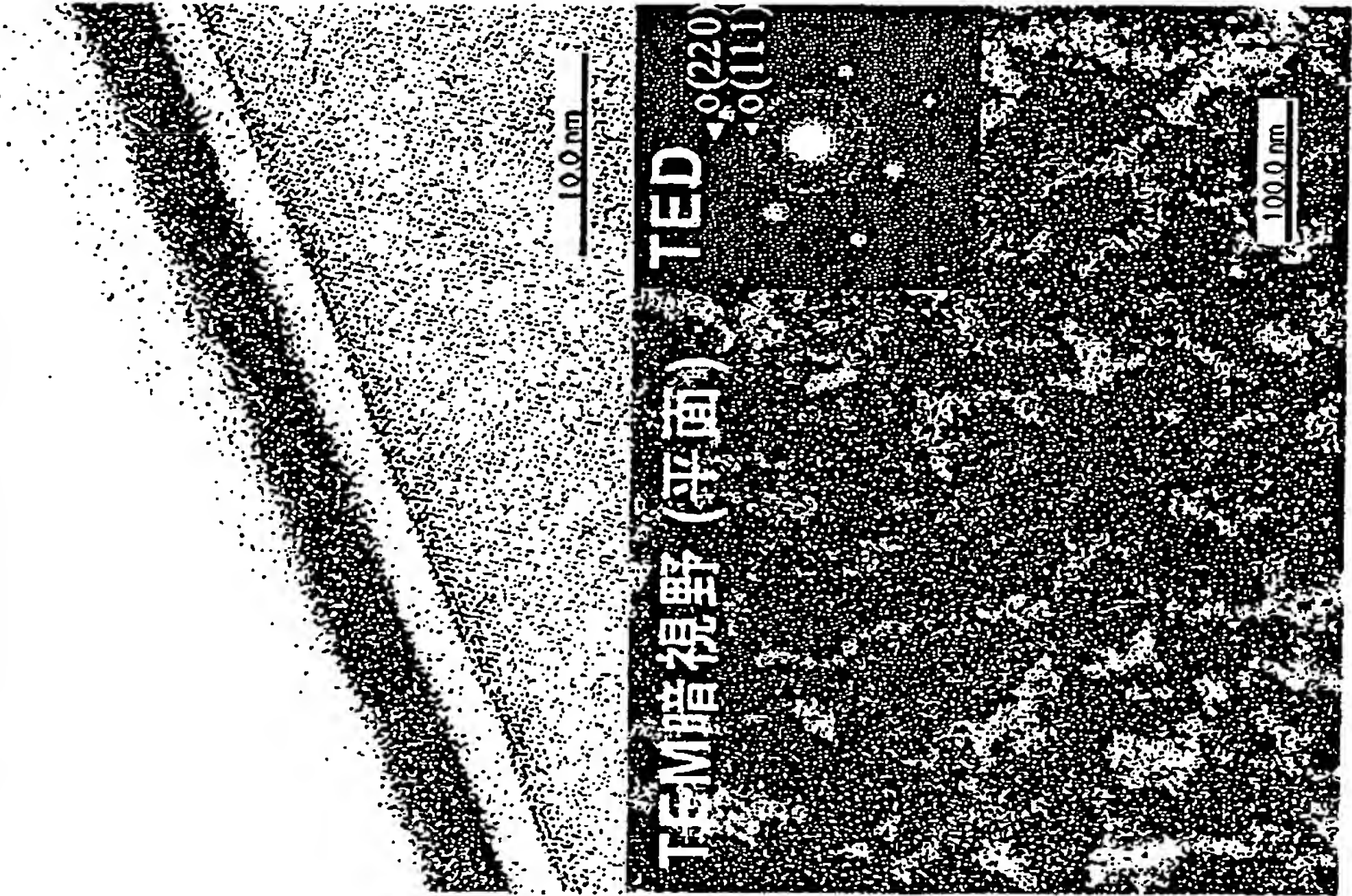


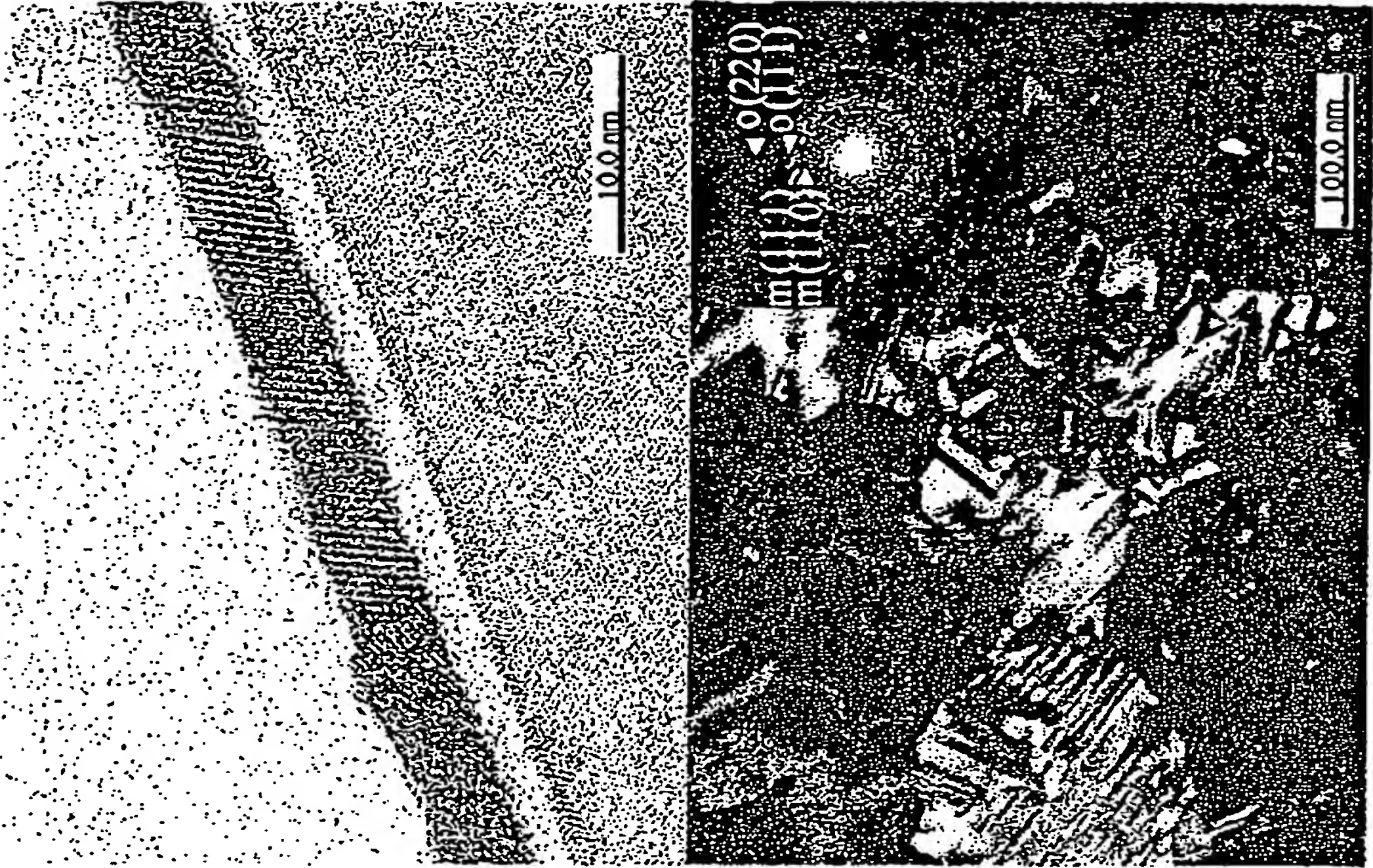
Fig. 6

(a) HfSiO

TEM (Sectional view)



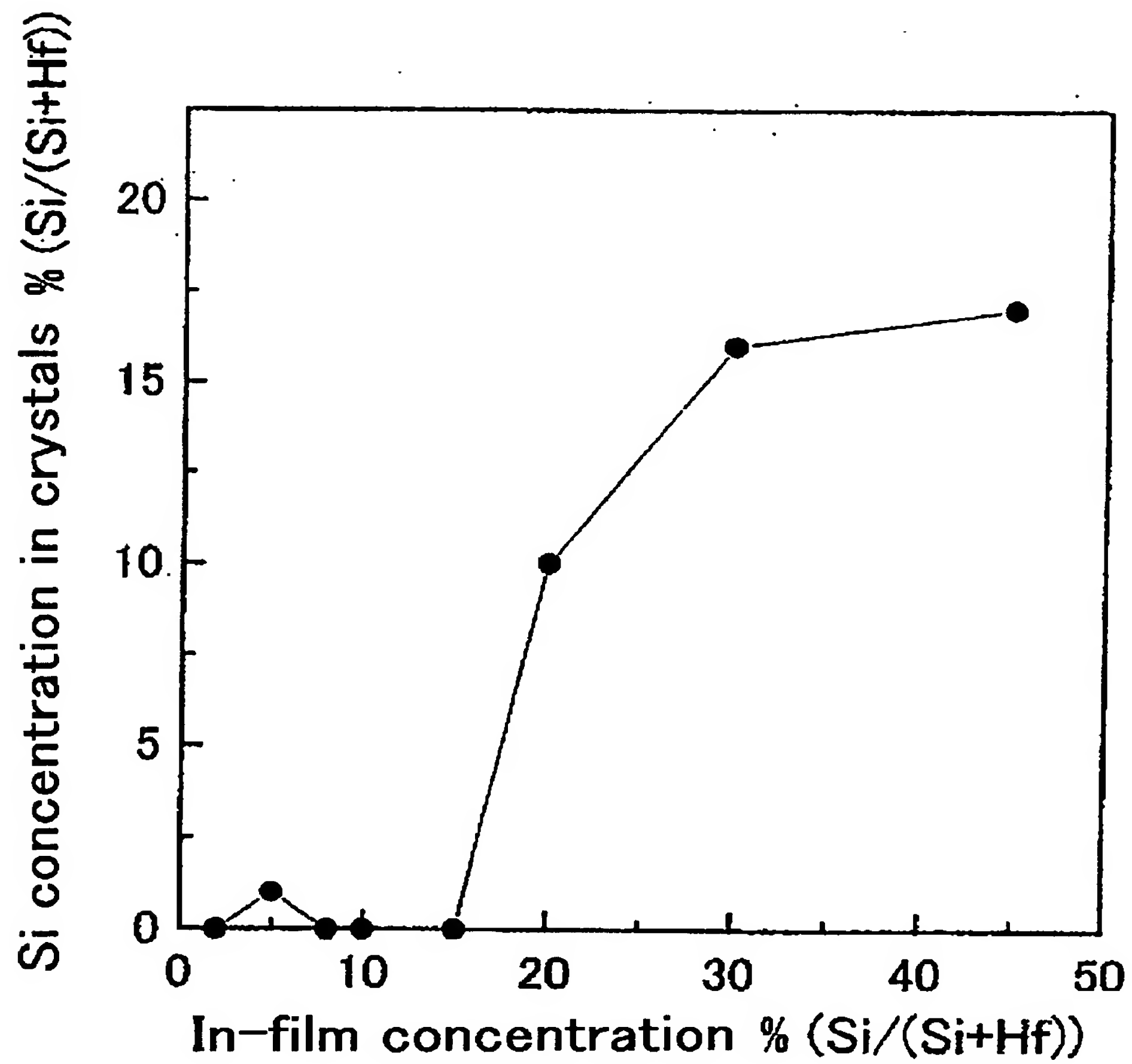
(b) HfO<sub>2</sub>



TEM Dark Field (Top plan view)

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Fig. 7





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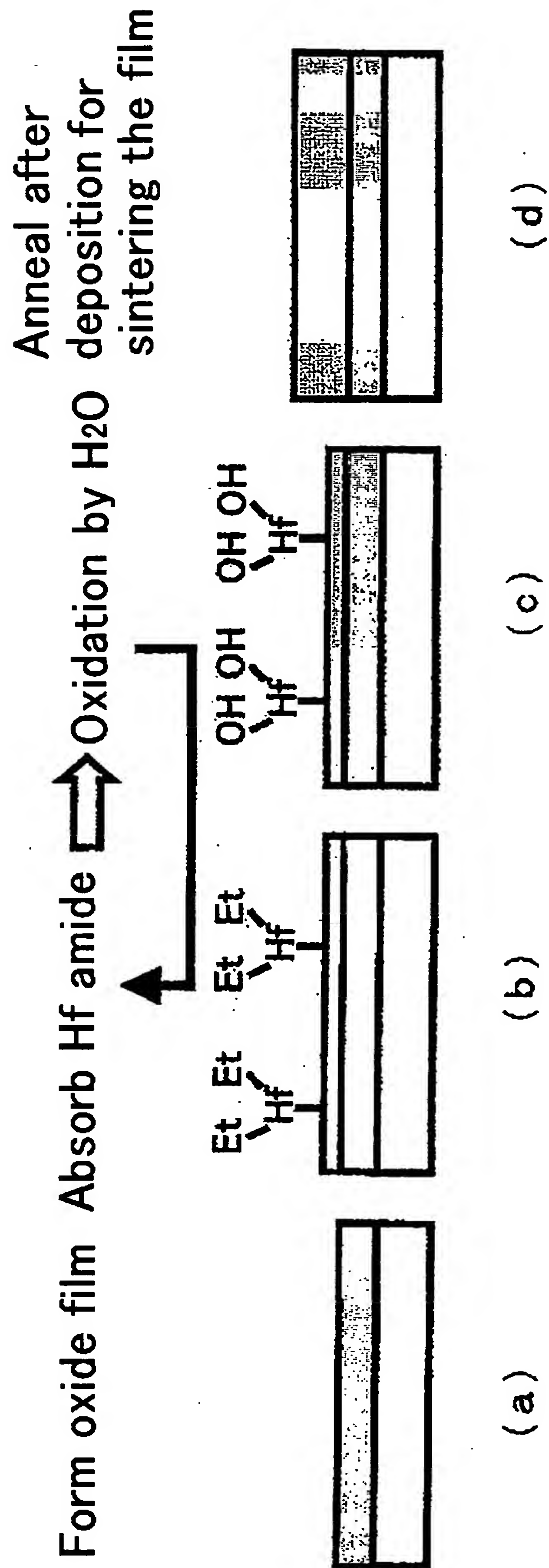




Fig. 9

Form oxide film      Form HfSiO film      Oxidation by oxygen      Anneal after deposition  
for sintering the film

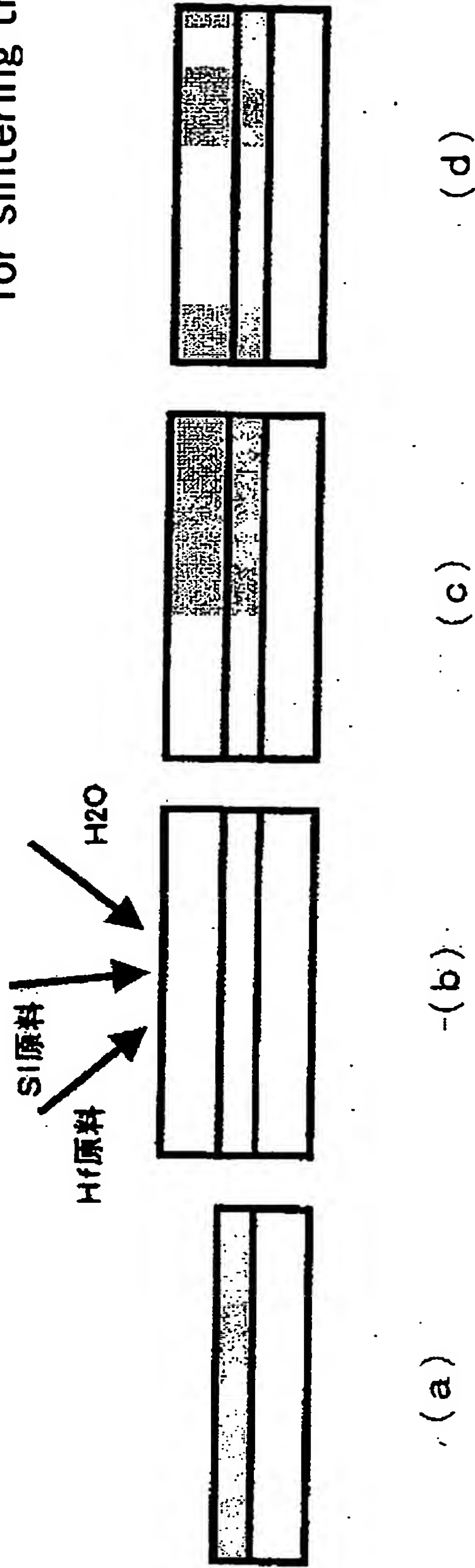


Fig. 10

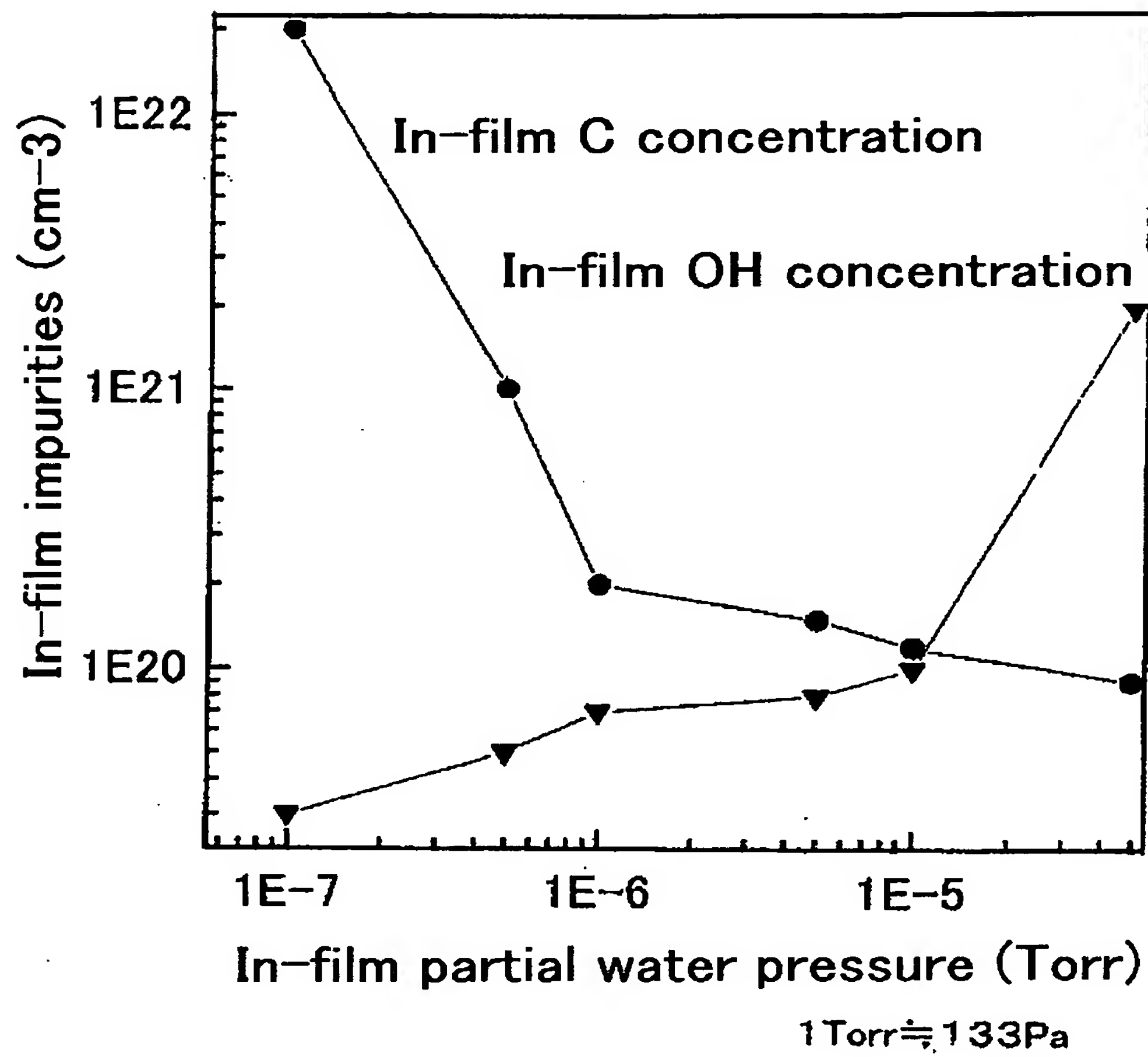


Fig. 11

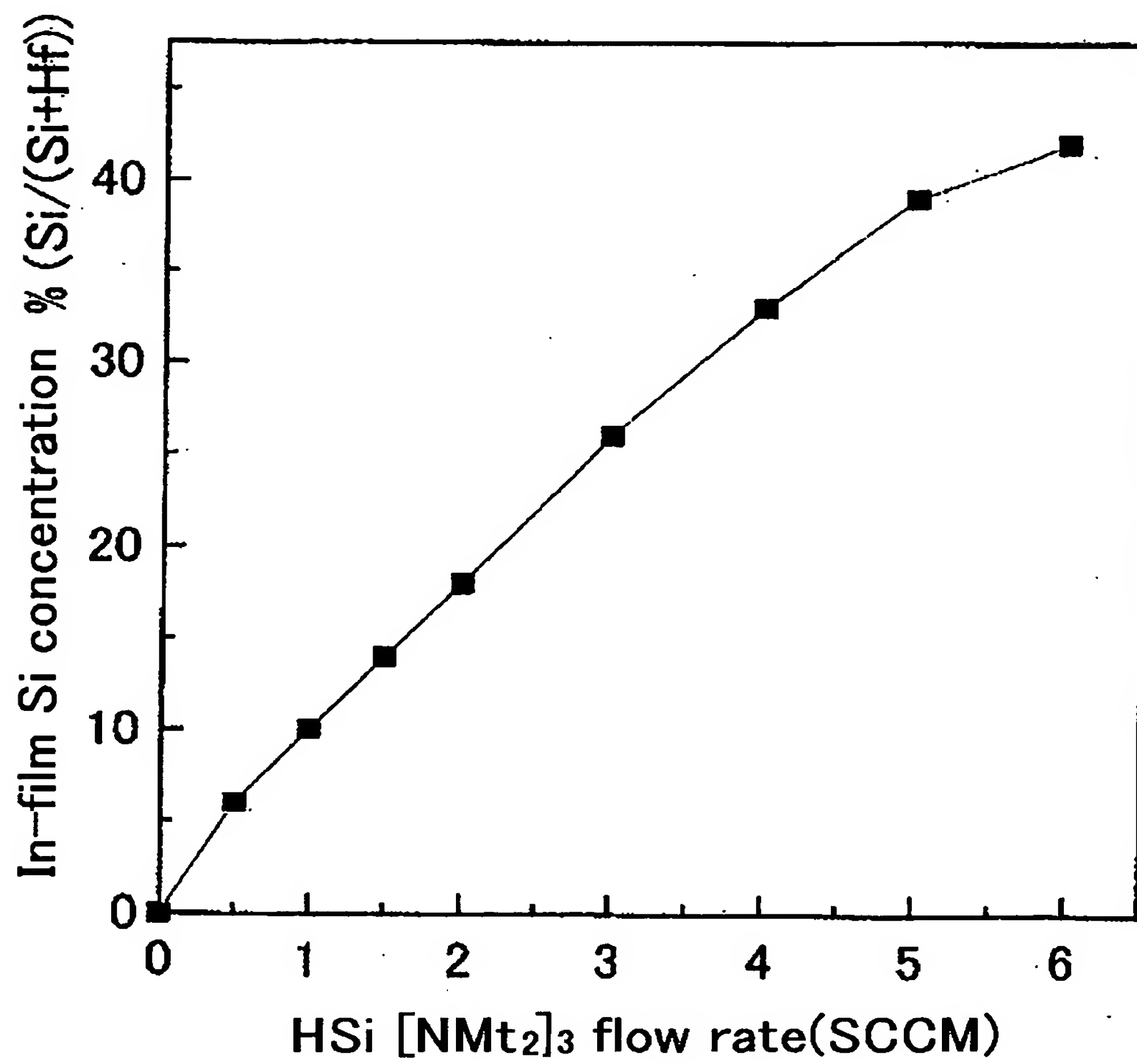


Fig. 12

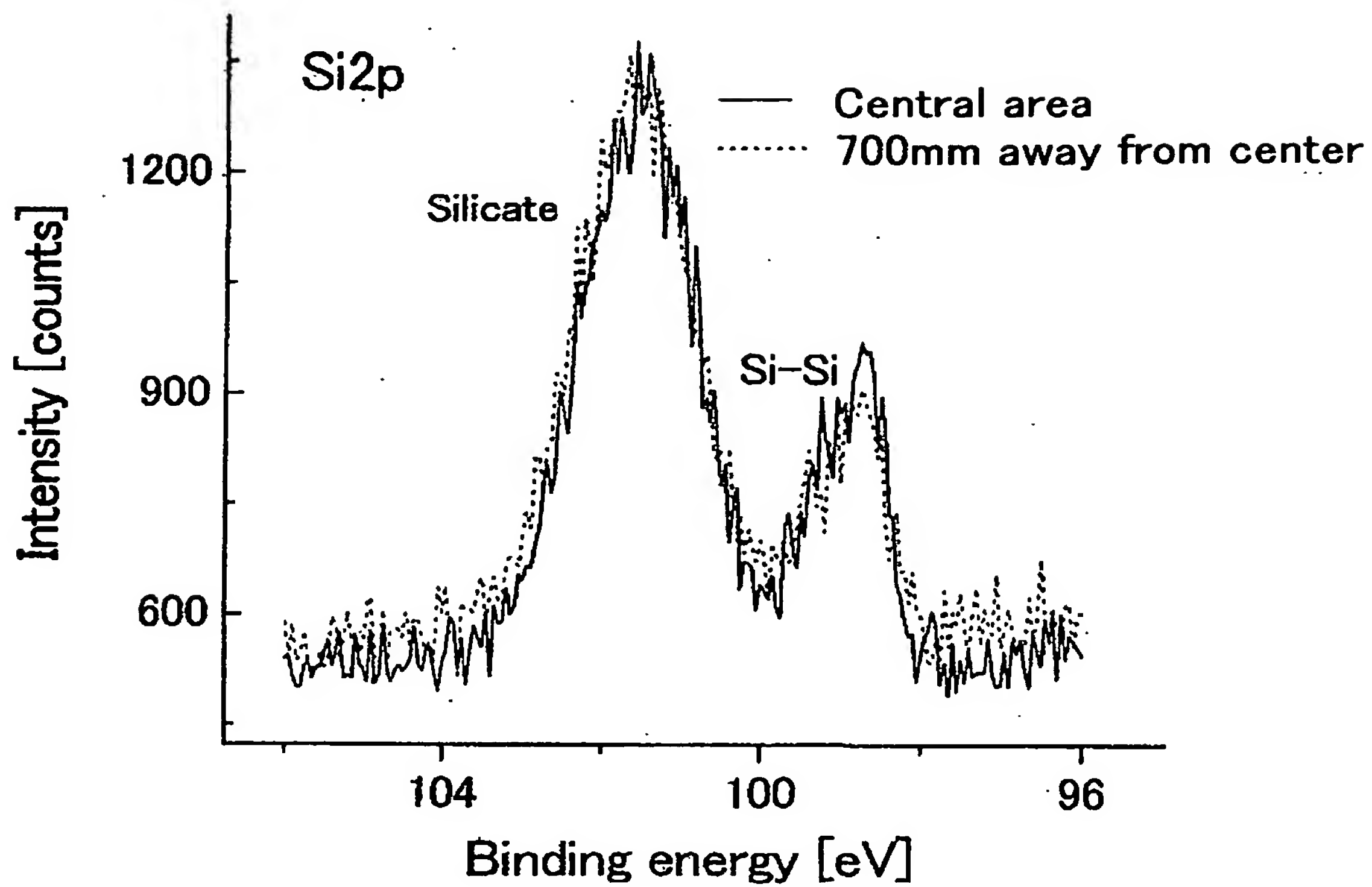


Fig. 13

